

Micro Modular System beyond AUTOMATION

► Introduction

W1300

Fully Auto Wafer Inspection

WI 300 Wafer Inspection Machine is designed to deliver utmost flexibility to support top vision inspection for fabricated components on wafer such as lens, LED & IC packages from 4" tiles to 6" wafer.

With unique blend of flexibility and high performance, it makes an ideal inspection solution for automation industry.



Inspection CriteriaMachine Specification









Machine Features • High Resoluton Camera

- Selection from 5MP to 65MP mono/color camera imaging technology
 Wafer Die and Wire Bond Inspection
- Cosmetic and Wire Bond Checking
- Auto Alignment Function
 2D decoding & Position Recognize (PR) vision
- Real Time Wafer Map Display
 All inspection information such as mapping map, defect region inspection results is visualized for easy reading
- Support Common Wafer Map Output Format STIF files
 Minimum Defect Size
 - 5 μm x 5 μm
- Confocal Displacement Sensor
- For warpage detection. Height compensation up to 2mm
 Multiple Unit Inspection in Single Grab

Inspection Criteria



Туре		
Wire Short	Double-Bond	
Wire Broken	Lifted Wire	
Wire Sagging	Lifted Ball	
Wire Sweeping	Ball Dimension	
Torn Bond	Particle on Die	
Wire Missing	Die Offset	
Epoxy Overflow	Lifted Stitch	
Lead Bent		
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Product 4" 6" ws

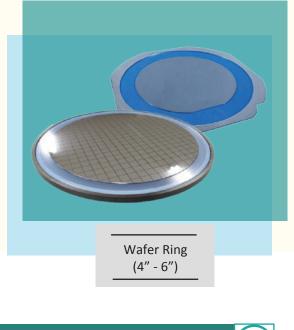
Machine Specification

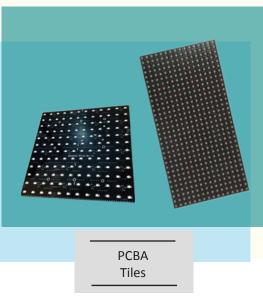


Product	4" – 6" wafer	
Specifications	Input:	Tiles, Wafer, Wafer rings
	Output:	Tiles, Wafer, Wafer rings
UPH	10K (single grab), 20K (multiple grab)	
Vision Inspection	Wire Bond and Cosmetic	
Inspection Area	6" x 6"	
Footprint	1250mm(W) x 2400mm(L) x 2050mm(H)	
Warranty	1 year limited excluding wear and tear parts	

Applicable Products







Other Products 📵





Laser Diode







COB LED
Test Machine



Reliability Test System